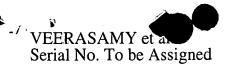
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depositing a coating on the substrate over at least a portion of the ion beam milled surface thereof.

B1 anders

- 40. (New) The method of claim 39, wherein said ion beam milling is performed so as to reduce the thickness of substantially the entire substrate by from about 4-20 Å.
- 41. (New) The method of claim 39, wherein the ion beam milling is performed using an ion energy of from about 1500-2000 eV.

REMARKS

This is a continuation of Serial No. 09/703,709. The original claims have been canceled, and new claims 39-41 have been added. It is respectfully requested that the application be amended as set forth above prior to initial examination thereof.

Respectfully submitted,

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